



INFORMATION DISCLOSURE CITATION <small>(Use several sheets if necessary)</small>				Docket Number (Optional) XA-9335		Application Number 09/615,081		
				Applicant(s) Yutaka SUENAGA et al.				
				Filing Date July 12, 2000		Group Art Unit 2872		
U.S. PATENT DOCUMENTS								
EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
J.T.	AA	5,737,137	04/07/98	Cohen et al.	359	859		
J.T.	AB	4,812,028	03/14/89	Matsumoto	350	444		
J.T.	AC	4,293,186	10/06/81	Offner	350	27		
J.T.	AD	5,734,496	03/31/98	Beach	359	362		
J.T.	AE	5,717,518	02/10/98	Shafer et al.	359	357		
J.T.	AF	5,742,436	04/21/98	Furter	359	727		
	AG							
	AH							
	AI							
	AJ							
	AK							
FOREIGN PATENT DOCUMENTS								
	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
J.T.	AL	WO 95/32446	11/30/95	WIPO	—	—	Abstract	
J.T.	AM	0 779 528	06/18/97	EPO	—	—		
	AN							
	AO							
	AP							
OTHER DOCUMENTS <small>(Including Author, Title, Date, Pertinent Pages, Etc.)</small>								
J.T.	✓	Owen, G. et al., "A Catadioptric Reduction Camera for Deep UV Microlithography", <u>Microelectronic Engineering</u> , Vol. 11, No. 1/04, April 1, 1990, pages 219-222.						
J.T.	✓	Haga, T. et al., "Large-Field (> 20 x 25mm ²) Replication by EUV Lithography", <u>Microelectronic Engineering</u> , Vol. 30, No. 1, 1996, pages 179-182						
EXAMINER				DATE CONSIDERED 04/13/01				
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								